# This Page Is Inserted by IFW Operations and is not a part of the Official Record

## **BEST AVAILABLE IMAGES**

Defective images within this document are accurate representations of the original documents submitted by the applicant.

Defects in the images may include (but are not limited to):

- BLACK BORDERS
- TEXT CUT OFF AT TOP, BOTTOM OR SIDES
- FADED TEXT
- ILLEGIBLE TEXT
- SKEWED/SLANTED IMAGES
- COLORED PHOTOS
- BLACK OR VERY BLACK AND WHITE DARK PHOTOS
- GRAY SCALE DOCUMENTS

### IMAGES ARE BEST AVAILABLE COPY.

As rescanning documents will not correct images, please do not report the images to the Image Problem Mailbox.

+713 623 4846

T-162 P.001/004 F-810

## FILE COPY

3040 Post Oak Blvd, Suite 1500 Houston, TX 77056-6582 TEL 713.623.4844 FAX 713.623.4846

WWW.MPSLLP.COM

## Moser Patterson & Sheridan, llp

ATTORNEYS AT LAW

#### **FACSIMILE COVER SHEET**

DATE:

December 16, 2003

**FILE NO:** 

AMAT/2592.C6/DSM/LOW K/JW

TO:

Office of Initial Patent Examination

**FAX NO:** 

(703) 746-9195

PHONE NO:

COMPANY:

USPTO

FROM:

B. Todd Patterson / Pennye Moses

PAGE(S) with cover:

4

**ORIGINAL TO** 

**FOLLOW?** 

☐ YES 図 NO

TITLE:

Method of Decreasing the K Value in SiOC Layer Deposited by

Chemical Vapor Deposition

U.S. SERIAL NO.;

10/632,179

FILING DATE:

July 31, 2003 Gaillard, et al.

INVENTOR: EXAMINER:

Unknown

**GROUP ART UNIT:** 

2812

CONFIRMATION NO.:

9827

#### CONFIDENTIALITY NOTE

The document accompanying this facsimile transmission contains information from the law firm of Moser, Patterson & Sheridan, L.L.P. which is confidential or privileged. The information is intended to be for the use of the individual or entity named on this transmission sheet. If you are not the intended recipient, be aware that any disclosure, copying, distribution or use of the contents of this faxed information is prohibited. If you have received this facsimile in error, please notify us by telephone immediately so that we can arrange for the retrieval of the original documents at no cost to you.

PATENT Atty, Dkt, No. AMAT/2592,C6/DSM/LOW K/JW

#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Gaillard, et al.

Serial No.: 10/632,179

Filed:

July 31, 2003.

Confirmation No.: 9827

For:

Method of Decreasing the

K Value in SiOC Layer Deposited by Chemical

Vapor Deposition

*ത* ത ത ത ത ത ത ത ത ത ത

Group Art Unit: 2812

Examiner:

Unknown

Commissioner for Patents
Office of Initial Patent Examination
Filing Receipt Corrections
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir.

CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office, Office of Initial Patent Examination, Fax No. (703) 746-9195, on the date below.

Date

Signature/

#### REQUEST FOR CORRECTION OF ERROR ON FILING RECEIPT

The Filing Receipt for the above-referenced application contains an error regarding the Domestic Priority Data.

Please insert the following Domestic Priority Data information:

a CIP of 09/553,461 04/19/2000 PAT 6,593,247

a CIP of 09/162,915 09/29/1998 PAT 6,287,990

a CIP of 09/185,555 11/04/1998 PAT 6,303,523

a CIP of 09/247,381 02/10/1999 PAT 6,348,725.

Attached is a copy of the Filing Receipt with the above change noted thereon.

Please correct this error or notify the applicants of the reasons for denying the request.

Respectfully submitted,

B. Todd Patterson

Registration No. 37,906

MOSER, PATTERSON & SHERIDAN, L.L.P.

3040 Post Oak Blvd. Suite 1500

Houston, TX 77056

Telephone: (713) 623-4844 Facsimile: (713) 623-4846

Agent for Applicant(s)

United States Patent and Trademark Office

ITED STATES DEPARTMENT OF COMMERCE.

ued Marion Pale-in and Trade-inack Office PC Data-50 Abrachia, Victor 22312-1430

APPL NO. | FILING OR 371 | ART UNIT | FIL FEB.RECD | ATTY.DOCKET NO | DRAWINGS | TOT CLMS | IND CLMS | 10/632,179 | 07/31/2003 | 2812 | 750 | AMAT/2592.C6/DSM/LOW K/JW | 7 | 20 | 3

**CONFIRMATION NO. 9827** 

' Patent Counsel APPLIED MATERIALS, INC. P.O. Box 450-A Santa Clara, CA 95052 FILING RECEIPT

FILING RECEIPT

FILING RECEIPT

FILING RECEIPT

FILING RECEIPT

FILING RECEIPT

Date Mailed: 11/03/2003

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Frederic Gaillard, Voiron, FRANCE:

Li-Qun Xia, Santa Clara, CA; 

Tian-Hoe Lim, Santa Clara, CA; 

Ellie Yieh, San Jose, CA; 

Wai-Fan Yau, Mountain View, CA; 

Shin-Puu Jeng, Tainan, TAIWAN; 

Katowei Liu, Santa Clara, CA; 

Yung-Cheng Lu, Taipei, TAIWAN;

Assignment For Published Patent Application

✓Applied Materials, Inc.;

Domestic Priority data as claimed by applicant

This application is a CON of 09/679,843 10/05/2000 PAT 6,627,532 which is a CIP of 09/465,233 12/16/1999 PAT 6,511,903 which is a CON of 09/021,788 02/11/1998 PAT 6,054,379

INSURE HERE \*

Foreign Applications

If Required, Foreign Filing License Granted: 10/28/2003

Projected Publication Date: 02/12/2004

Non-Publication Request: No